Electrically injected GeSn laser on Si substrate operating up to 130 K.

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Germanium-tin (GeSn) semiconductors have gained significant attention over the last years as a group IV material for the development of novel Si-based optoelectronic devices. Specifically, direct band gap GeSn alloys with Sn fractions above 8% are of interest as light emitting sources in the near- and mid-infrared spectral range. In addition, GeSn epitaxy is monolithic on Si and also fully compatible with the complementary metal-oxide semiconductor (CMOS) technology, making it a promising candidate for the integrated light source on the Si platform, with advantages such as cost-effectiveness, reliability, and compactness [2]. Recently, GeSn lasers on Si substrate were demonstrated both under optical pumping and electrical injection. In this work, we report an electrically injected GeSn/SiGeSn laser grown on Si substrate operating up to 130 K. Our study is mainly focused on the cap layer effect on the optical loss for lasing devices. The GeSn/SiGeSn heterostructure was grown using chemical vapor deposition (CVD) technique. The laser devices were fabricated in ridge waveguide structures with 80 μ m, 100 μ m and 120 μ m wide ridges. The lasing performance was investigated under pulsed conditions. The electroluminescence signal was collected through a monochromator and liquid-nitrogencooled InSb detector (response range 1-5.5 µm). The L-I characteristics of devices with different cavity lengths were studied at different temperatures. Our results suggest pathways for enhancing the lasing performance of electrically injected GeSn laser diodes.



Figure1 Temperature dependent L-I curve.

Figure 2(a, b) : Lasing spectra at and above threshold for 77K and 130 K temperature respectively

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[2] Solomon Ojo, Yiyin Zhou, Sudip Acharya, Nicholas Saunders, Sylvester Amoah, Yue-Tong Jheng, Huong Tran, Wei Du, Guo-En Chang, Baohua Li, Shui-Qing Yu, "Silicon-based electrically injected GeSn lasers," Proc. SPIE 11995, Physics and Simulation of Optoelectronic Devices XXX, 119950B (4 March 2022); https://doi.org/10.1117/12.2615476